



Attorney Docket: 081468-0307015
Client Reference: P-1749.000-US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:
TEN BERGE et al.

Confirmation Number: 8897

Application No.: 10/724,403

Group Art Unit: 2826

Filed: December 1, 2003

Examiner: LEONARDO ANDUJAR

Title: SUBSTRATE, METHOD OF PREPARING A SUBSTRATE, METHOD OF MEASUREMENT, LITHOGRAPHIC APPARATUS, DEVICE MANUFACTURING METHOD AND DEVICE MANUFACTURED THEREBY, AND MACHINE-READABLE STORAGE MEDIUM

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

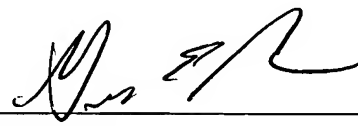
REQUEST FOR INITIALED PTO-1449 FORM

Applicants gratefully acknowledge receipt of the Notice of Allowability dated March 29, 2007.

Applicants note that the Examiner did not return an initialed copy of the PTO-1449 form filed with the Information Disclosure Statement on December 1, 2003. Attached is a copy of the stamped Postcard, Information Disclosure Statement and PTO-1449 form filed on December 1, 2003. Applicants respectfully request that the Examiner acknowledge consideration of the cited references by signing, dating, and returning (to the undersigned) the enclosed copy of the PTO-1449 form.

Date: April 13, 2007

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Guillermo E. Baeza
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COPY



PTO RECEIPT Attorney Docket: 081468-0307015

Atty: Kerry T. Hartman/

Appln. No: Date: December 1, 2003

Inventor(s): PETER TEN BERGE ET AL.

Title: SUBSTRATE, METHOD OF PREPARING A SUBSTRATE,
METHOD OF MEASUREMENT, LITHOGRAPHIC APPARATUS, DEVICE
MANUFACTURING METHOD AND DEVICE MANUFACTURED
THEREBY, AND MACHINE-READABLE STORAGE MEDIUM

- ☐ Preliminary Amendment ☒ Application Data Sheet
☐ Appendix ☒ Utility/Design/Provisional

☒ 26 No. of Pages Application (Spec + Claim(s) + Abstract)

☐ No. of Pages Separate Power of Attorney

☒ 28 No. of Numbered Claims Only

☐ Declaration (of pages)

☐ Assignment ☐ Cover Sheet

☐ No. of Priority Documents

☒ 3 No. of Sheets of Drawings (Fig(s) 6)

☒ IDS ☐ Appendix for Cited Appl(s) ☐ Foreign Search Report/OA

☒ PTO-1449 ☒ Cited Documents ☐ Nonpublication Request

\$ Total Fee Charged to Deposit Account 033975

Other: CURRENT DUE DATE: December 1, 2003



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Atty: Kerry T. Hartman/

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22386 U.S. PTO
10/724403



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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of

PETER TEN BERGE, et al.

Group Art Unit:

Application No.:

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For: SUBSTRATE, METHOD OF PREPARING A SUBSTRATE, METHOD OF MEASUREMENT, LITHOGRAPHIC APPARATUS, DEVICE MANUFACTURING METHOD AND DEVICE MANUFACTURED THEREBY, AND MACHINE-READABLE STORAGE MEDIUM

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Sir:

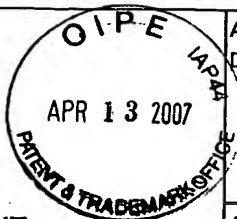
Pursuant to 37 CFR 1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date of this non-CPA application. No certification or fee is required.

Respectfully Submitted,

Kerry T. Hartman
Registration Number 41818

Date: December 1, 2003
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Dkt. No.

M#

Client Ref.

0307015

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**INFORMATION DISCLOSURE STATEMENT
BY APPLICANT**

Applicant: TEN BERGE et al.

Appln. No.: New Herewith

Filing Date: December 1, 2003

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Page

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of

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Examiner: Unknown

Group Art Unit: Unknown

U.S. PATENT DOCUMENTS

Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR					
	BR					
	CR					
	DR					
	ER					
	FR					
	GR					

FOREIGN PATENT DOCUMENTS

		Document Number	Date MM/YYYY	Country	Inventor Name		Abstract		Readily Available	
							Enclosed	No	Enclose	No
	HR									
	IR									
	JR									
	KR									

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

LR	Mattias Vangbo et al., High Precision Crystallographic Alignment of InP(100), Electrochemical and Solid-State Letters, 2(8) 1999, pp. 407-408.				
MR	G. Ensell, Alignment of mask patterns to crystal orientation, Sensors and Actuators A 53, (1996) pp. 345-348.				
NR	Mattias Vangbo et al., Precise mask alignment to the crystallographic orientation of silicon wafers using wet anisotropic etching, J. Micromech. Microeng. 6 (1996) pp. 279-284.				
OR	J. M. Lai et al., Precision alignment of mask etching with respect to crystal orientation, J. Micromech. Microeng. 8 (1998) pp. 327-329.				
PR					
QR					

Examiner

Date Considered:

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.